



Load Mask:

Place mask holder upside down on the small mask holder table (located on the left side of the system). Press the CHANGE MASK button (located near the top right side of the chassis). Place photo mask chrome side up on mask holder. Press photo mask up and to the left so that it rests against the screws to ensure proper placement. Press the ENTER button to activate the photo mask vacuum. Press down on the metal clip below the photo mask causing the black bar to spring up and help lock the mask in place. Carefully slide Mask holder and mask into the mask holder slot on the MA6. Press the CHANGE MASK button.

Load Wafer Chuck:

Place wafer chuck carefully on slide.

Edit Parameters:

Press the EDIT PARAMETERS button (located on the right side of the chassis). Enter your choice of options with the X and Y KEYS. The Y keys will move up or down through the Modes and the X keys will change the values. Once you have set your exposure mode and exposure parameters press the EDIT PARAMETERS button again to begin your exposure.

Wafer exposure:

Press the LOAD button. The green screen will tell you to “pull slide and load wafer”. Place the flat of the wafer against the two pins at the bottom and move the wafer against the last pin on the left. When the wafer is on the chuck press the ENTER button. This will turn on the chuck vacuum. The green screen will say “Push slide into system”. Push slide into aligner and press the ENTER button. The wafer will move up from the slide and into CONTACT with the mask. The Orange CONTACT light will come on and then the wafer will drop down the alignment gap to what was set in the EDIT PARAMETERS step. The green screen will now say ALIGN WAFER. You can now use the micrometers to move your sample.

Microscope Alignment:

Turn the monitor on. Select Top Side Microscope or Back Side Microscopes by pressing the BSA button (located near the bottom right of the key pad) if the BSA button is lit up